

L Numbr	Hits	Search T xt	DB	Time stamp
-	680	(345/30,55,84).ccls.	USPAT; US-PGPUB	2003/02/13 18:12
-	3	("5061049" "5583688" "6147790").pn.	USPAT; US-PGPUB	2003/02/13 18:16
-	2691	(mems or microelectr mechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:19
-	3369	(mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:20
-	0	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3) and (semiconduct\$3 with substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:20
-	734	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3) and (semiconduct\$3 with substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:20
-	120	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3) and (semiconduct\$3 with substrate)) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:21
-	3	(((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3) and (semiconduct\$3 with substrate)) and torsion\$2) and (switch\$3 same voltage)) and (memory same stor\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:21
-	1711	(359/223,224,290-292,298).ccls. (345/85).ccls.	USPAT; US-PGPUB	2003/02/13 18:25
-	29	(((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3) and (semiconduct\$3 with substrate)) and torsion\$2) and (switch\$3 same voltage)	USPAT; US-PGPUB; EPO; JPO; DERWENT;	2003/02/14 12:28
-	6262	(mems or microelectromechanical or (micro adj electro adj mechanical))	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:44
-	1128	((mems or microelectromechanical or (micro adj electr adj m chanical))) and semiconduct\$3 n ar5 substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:43

	114	((mems or microelectromechanical or (micro adj electro adj mechanical))) and semiconduct\$3 near5 substrate) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:29
	38	((((mems or micro electromechanical or (micro adj electro adj mechanical))) and semiconduct\$3 near5 substrate) and torsion\$2) and (driv\$3 with voltage)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:30
	12	(((((mems or microelectromechanical or (micro adj electro adj mechanical))) and semiconduct\$3 near5 substrate) and torsion\$2) and (driv\$3 with voltage)) and memory	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:35
	23	(((((mems or microelectromechanical or (micro adj electro adj mechanical))) and semiconduct\$3 near5 substrate) and torsion\$2) and memory) not (((((mems or microelectromechanical or (micro adj electro adj mechanical))) and semiconduct\$3 near5 substrate) and torsion\$2) and (driv\$3 with voltage)) and memory)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:35
	115	((mems or microelectromechanical or (micro adj electro adj mechanical))) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:04
	6262	(mems or microelectromechanical or (micro adj electro adj mechanical))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:03
	115	((mems or microelectromechanical or (micro adj electro adj mechanical))) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:39
	7	(US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.	USPAT; US-PGPUB	2003/02/14 13:38
	1	US-20020076138-A1.DID. and ((mems or microelectromechanical or (micro adj electro adj mechanical)))	USPAT; US-PGPUB	2003/02/14 13:38
	7	((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)))	USPAT; US-PGPUB	2003/02/14 13:38

	3	((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or micr electr m chanical or (micr adj I ctro adj m chanical))) and (((mems or micr electromechanical or (micro adj electro adj mechanical))) and semiconduct\$3 near5 substrate)	USPAT; US_PGPUB	2003/02/14 13:38
	4	((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical))) and torsion\$2 (micro adj mirror) or micromirror	USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:40
	3580		USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:40
	3073	((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)))	USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:56
	1711	((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)	USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:42
	25	(((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and (memory same capacitor\$1)	USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:46
	173	(((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate	USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:43
	30	(((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (memory same capacitor\$1)) (((((micro adj mirror) or micromirror) not ((mems or micro lectr mechanical or (micr adj electro adj mechanical))) and (actuat\$3 or torsi n\$2 r driv\$3)) and (m m ry same capacit r\$1))	USPAT; US_PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:44

	67	((((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectr mechanical or (micr adj electr adj mechanical))) and t rsi n\$2) (((((micr adj mirror) or micromirr r) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:45
	63	((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:45
	67	(((((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical))) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:45
	4025	"67" and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 14:19
	10	((((((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical))) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:52

	2	6266178.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT	2003/02/14 13:52
	5	(US-6473361-\$ r US-6242989-\$ r US-5867302-\$ or US-6046840-\$ r US-6266178-\$).did.	USPAT;	2003/02/14 14:19
	5	((US-6473361-\$ or US-6242989-\$ or US-5867302-\$ or US-6046840-\$ or US-6266178-\$).did.) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT;	2003/02/14 16:08
	9335	((mems or microelectromechanical or (micro adj electro adj mechanical))) ((micro adj mirror) or micromirror)	US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/14 16:08
	55	((mems or microelectromechanical or (micro adj electro adj mechanical))) ((micro adj mirror) or micromirror) and ((memory adj cell) with driv\$3)	EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/14 16:10
	67	((mems or microelectromechanical or (micro adj electro adj mechanical))) ((micro adj mirror) or micromirror) and ((memory adj cell\$1) with driv\$3)	DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/14 16:10
	5	((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (memory same capacitor\$1)	EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/19 11:35
	3	((((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (memory same capacitor\$1)) and (memory adj cell\$1)	EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/14 17:15
	9370	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)))	DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/19 14:56
	251	((micro adj mirror) or micromirror) or (mems or microelectromechanical or (micro adj electro adj mechanical))) and (memory adj2 cell)	EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB;	2003/02/19 15:09

	12	((micro adj mirror) or micromirror) or ((mems or micro electro mechanical or (micro adj electro adj mechanical))) and ((memory adj2 cell) same capacitor\$1 same transistor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:57
	12	(((micro adj mirror) or micromirror) or ((mems or micro electro adj mechanical))) and ((memory adj2 cell)) and ((memory adj2 cell) same capacitor\$1 same transistor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:57
	44	(((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and ((memory adj2 cell)) and ground)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:25
	5	(((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and ((memory adj2 cell)) and (ground same reset\$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:52
	17	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and (pass adj transistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:53
	11	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and ((pass adj transistor) same capacitor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:58
	2	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and ((pass adj transistor) same capacitor same gate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:00
	64	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and ((transistor) same capacitor same gate) and ground\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:00
	37	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical))) and ((transistor) same capacitor same gate) and (transistor same ground\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:26
	2	5285407.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:26